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**OPTIMIZATION OF THE ELECTROSTATIC STRUCTURE OF THE ION MICROPROBE**

The paper presents optimization data obtained for an immersion probe-forming system of the ion microprobe to be used in 3 MeV H<sup>+</sup> ion accelerator generating 0,4 μm beam spot for normalized acceptance of 7 μm<sup>2</sup>· mrad<sup>2</sup>. MeV. To achieve higher microprobe resolution it is intended to place an electrostatic lens between the collimators and the accelerating tube.

*Keywords:* ion beam; immersion probe-forming system; optimizations; electrostatic accelerator.